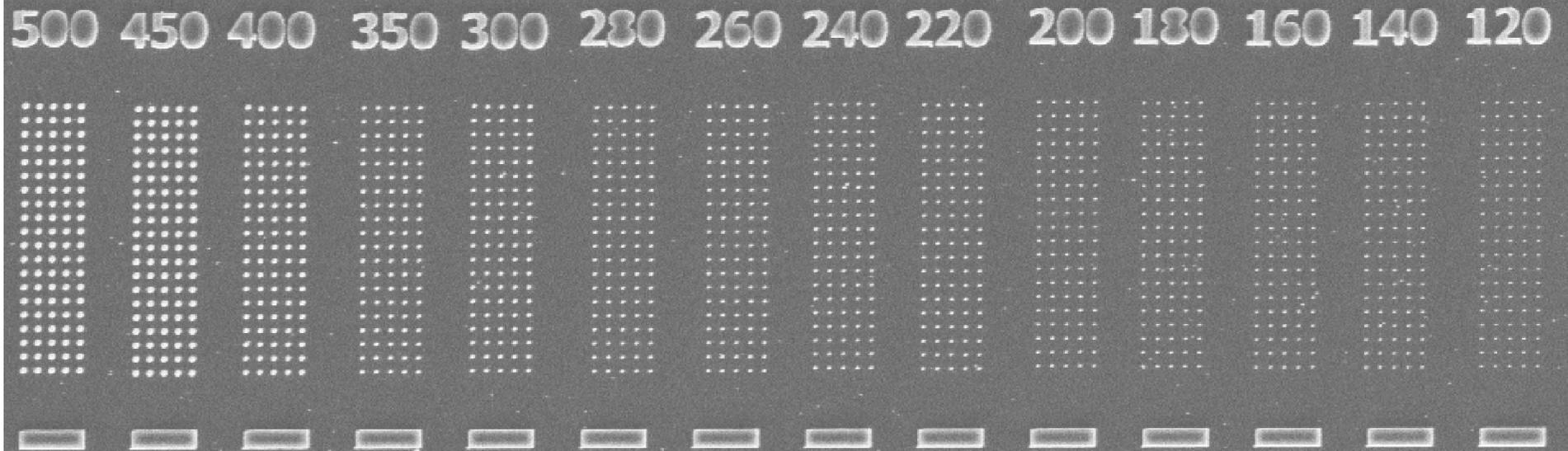
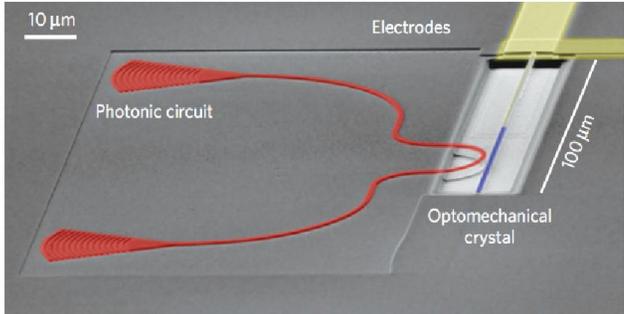
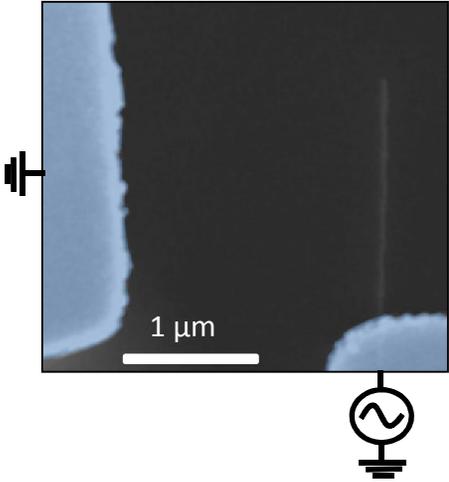
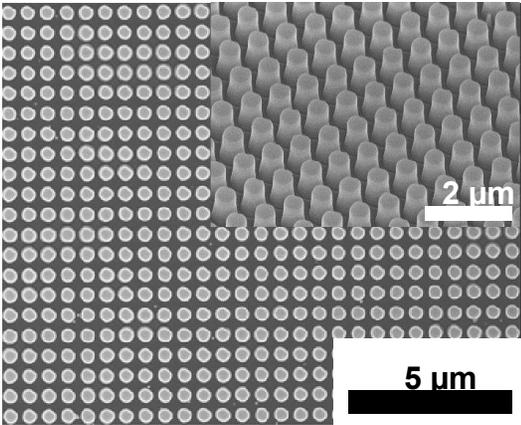
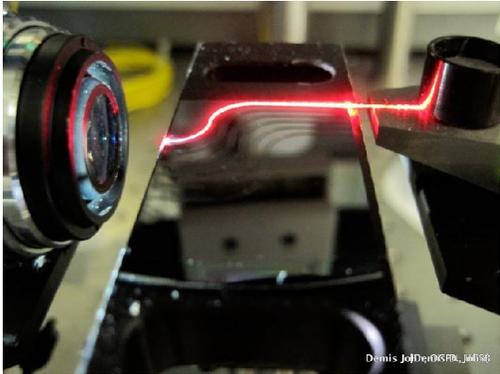
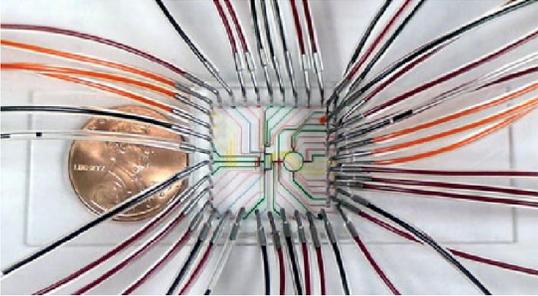
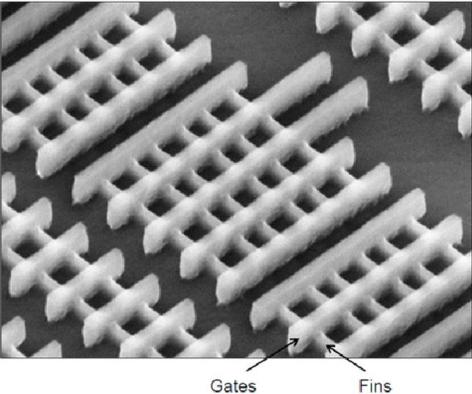


# Semiconductor Processing: Crystal Growth

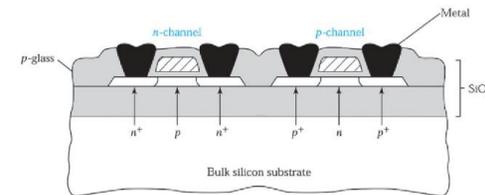
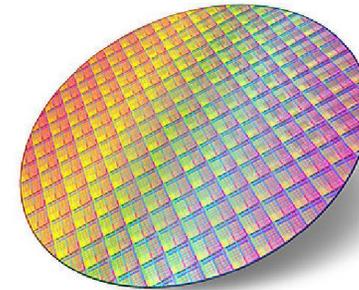
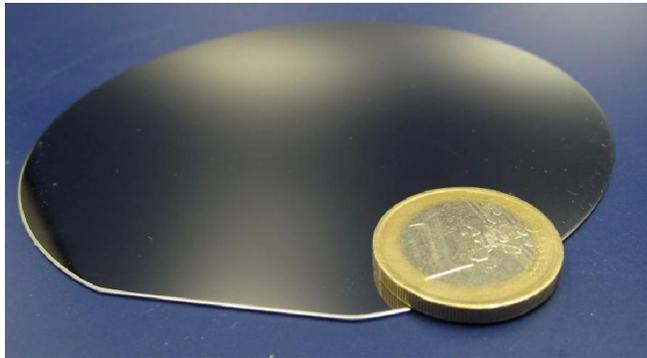


Professor Benjamín Alemán  
Department of Physics  
University of Oregon

# How do we make these useful and curious structures?



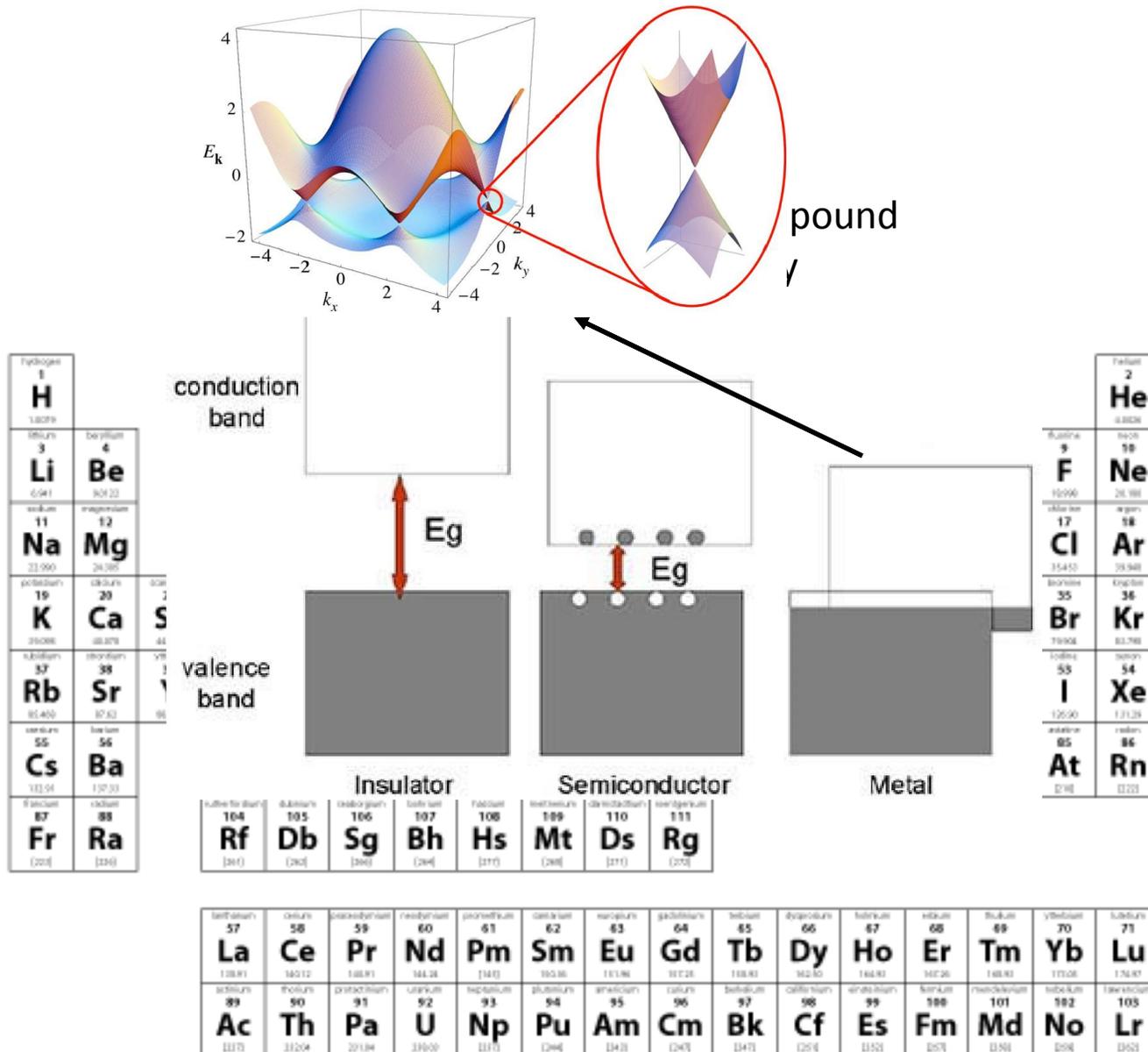
# Planar Processing with Semiconductors (Silicon): Course Map



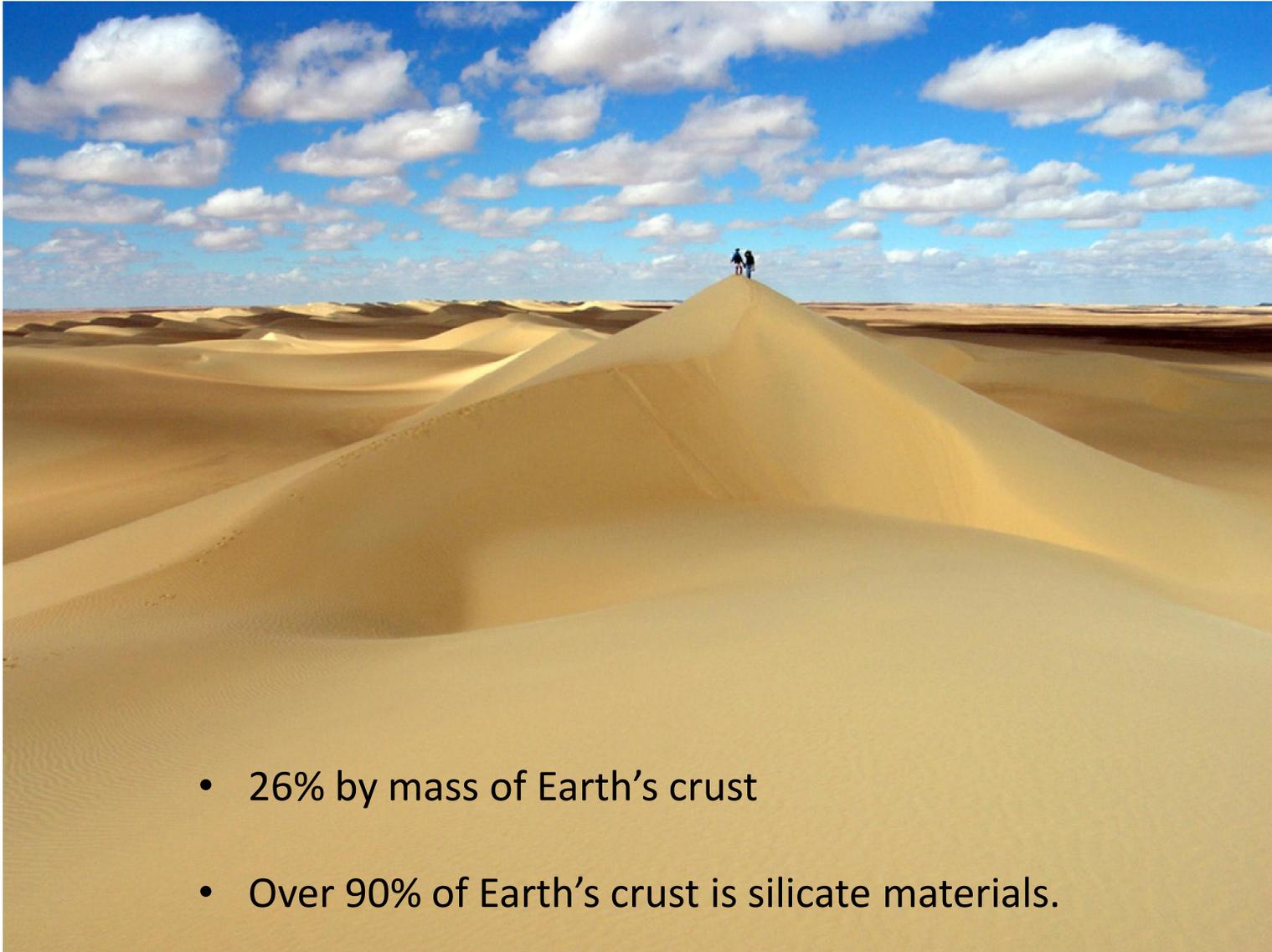
- Crystal growth (semiconductors)
- Wafer characteristics
- Wafer doping
- Defects and impurities
- ( $\text{SiO}_2$  growth)

- ( $\text{SiO}_2$  growth)
- Masked doping
- Lithography
- Vacuum Systems
- Thin Films: CVD, MBE, PVD, ALD
- Implantation
- Wet and Dry Etching
- Integration

# Why are semiconductors useful?



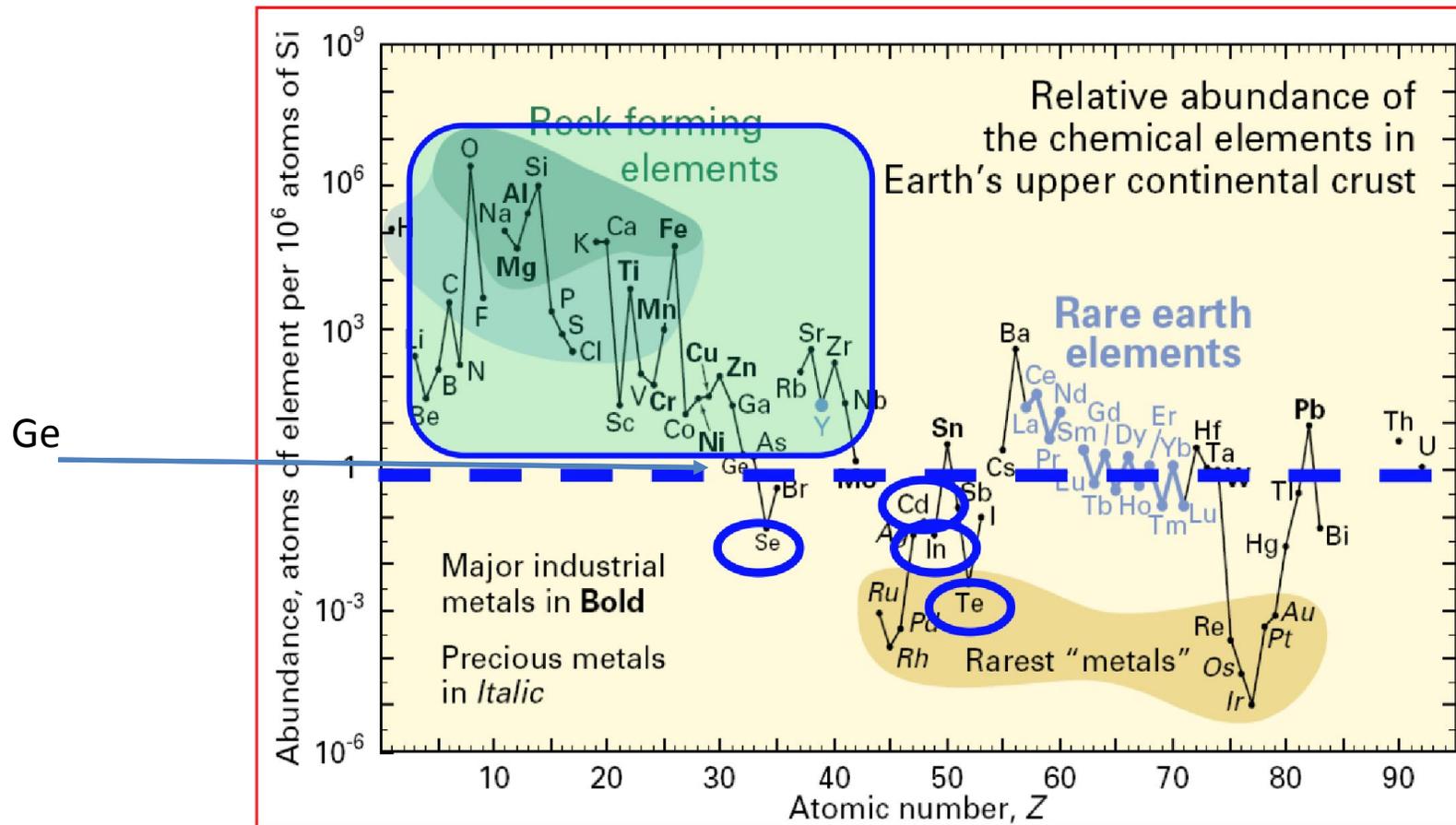
# Why is Silicon an important semiconductor and why is it so popular in planar processing?



- 26% by mass of Earth's crust
- Over 90% of Earth's crust is silicate materials.

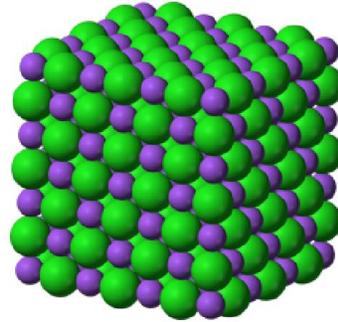
# Silicon is abundant

## Relative abundance of elements vs. atomic number\*



*\*from P.H. Stauffer et al, Rare Earth Elements - Critical Resources for High Technology, USGS (2002)*

# A brief introduction to crystal structure

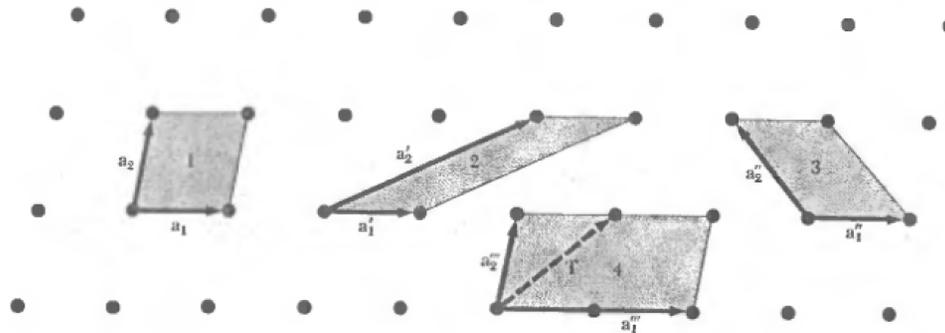


Crystal Structure = Lattice + Basis

A *lattice* is defined by a set of fundamental translation vectors  $\mathbf{a}_1, \mathbf{a}_2, \mathbf{a}_3$ , such that the atomic arrangement looks the same from the perspective of both  $\mathbf{r}$  and  $\mathbf{r}'$ , where

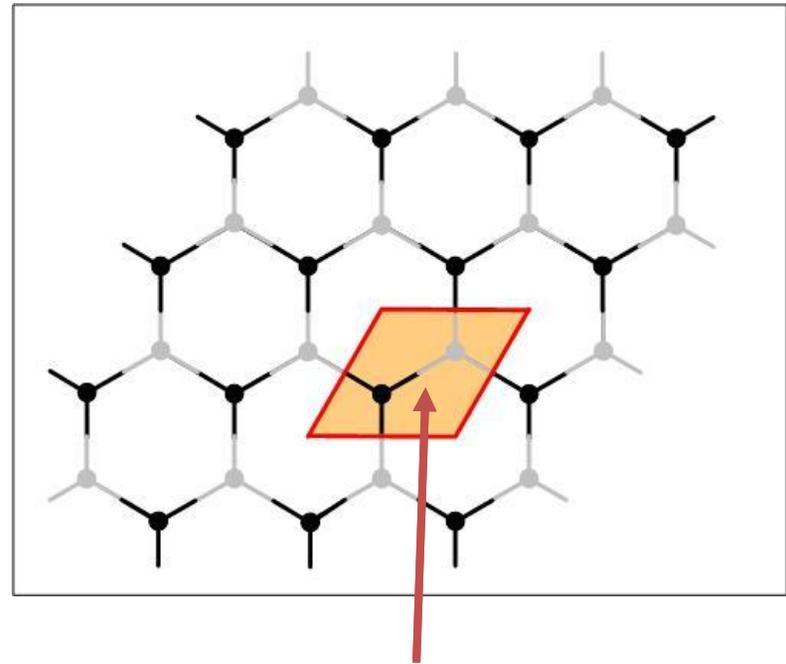
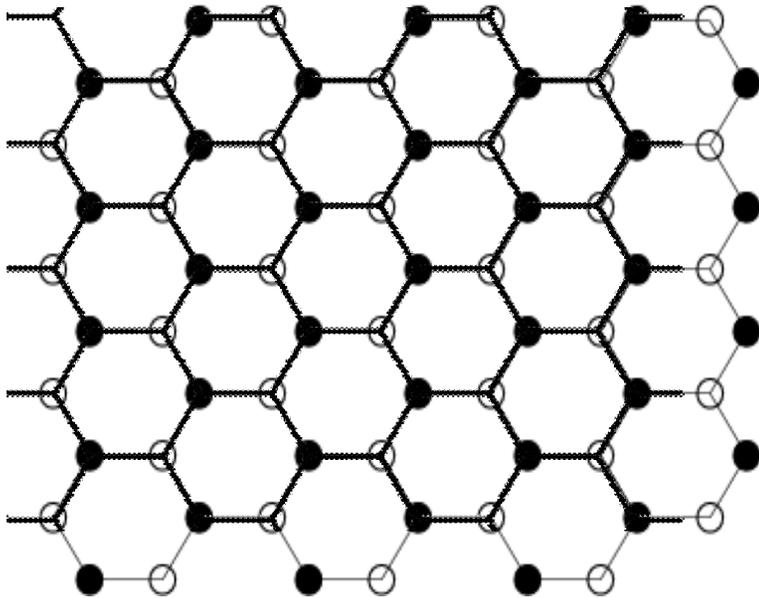
$$\mathbf{r}' = \mathbf{r} + u_1 \mathbf{a}_1 + u_2 \mathbf{a}_2 + u_3 \mathbf{a}_3$$

and  $u_1, u_2, u_3$  are arbitrary integers.



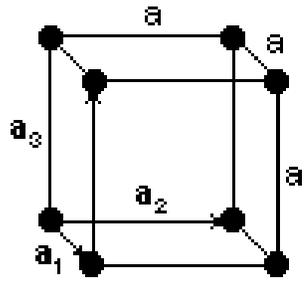
# The basis

Lattice?

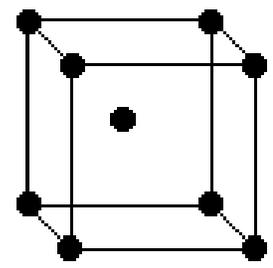


Basis

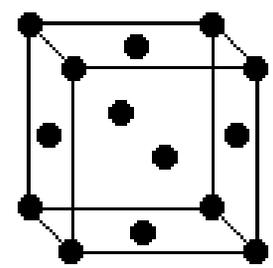
# Cubic lattices



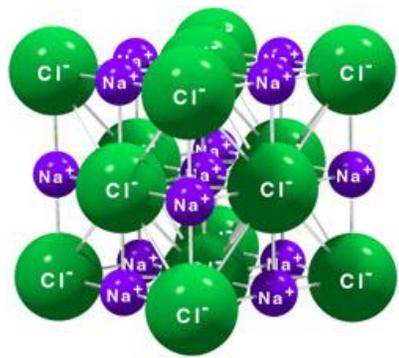
simple  
 $n = 1$



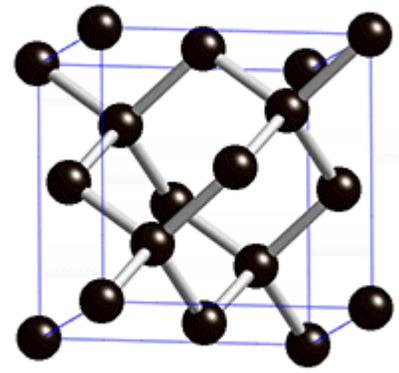
body-centered  
 $n = 2$



face-centered  
 $n = 4$



Salt is FCC with basis containing one Na and one Cl.



Diamond is FCC with two identical basis atoms:

All group IV elements can crystallize into diamond, including *C* and *Si*.

# Index system for crystal planes

Crystal planes are identified using Miller indices in the following way:

1. Find the intersection of the axes in terms the basis of the fundamental translation vectors  $\mathbf{a}_1, \mathbf{a}_2, \mathbf{a}_3$ .
2. Take the reciprocal and reduce to three integers having the same ratio, usually the smallest three integers. The result is enclosed in parentheses  $(hkl)$  and called the index of the plane. Negative integers are denoted with bars  $(h\bar{k}l)$ .

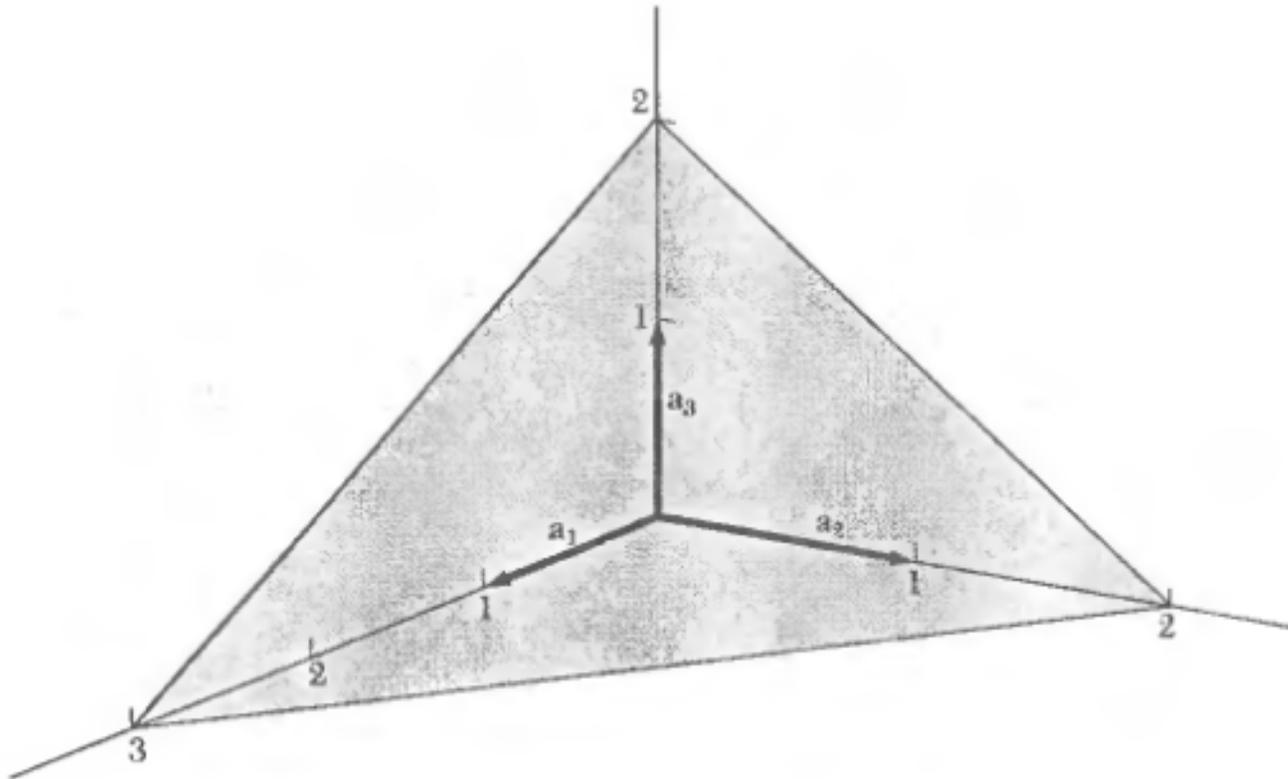
Also, planes equivalent by symmetry are denoted with braces  $\{hkl\}$ .

- The set of cube faces is  $\{100\}$ .

The indices  $[uvw]$  of a direction in a crystal are the set of the smallest integers that have the ratio of the components of a vector in the desired direction.

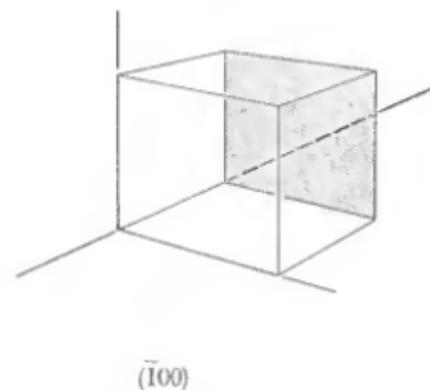
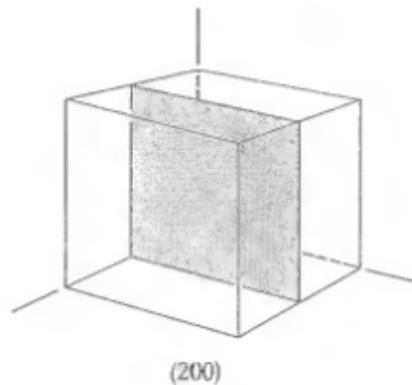
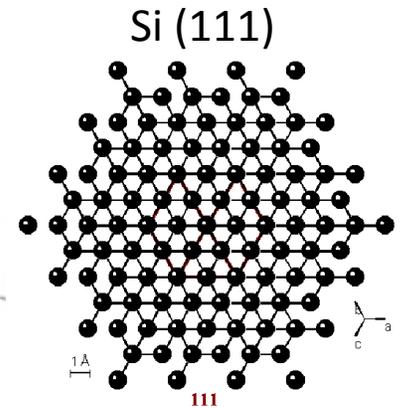
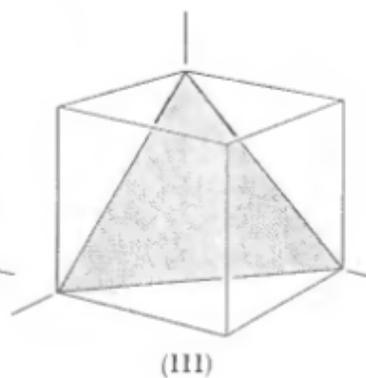
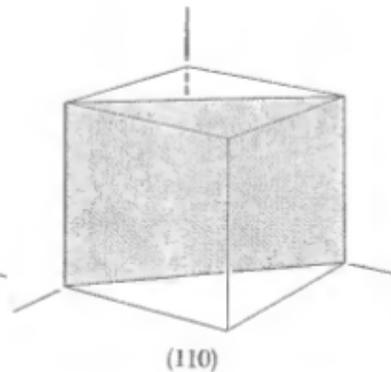
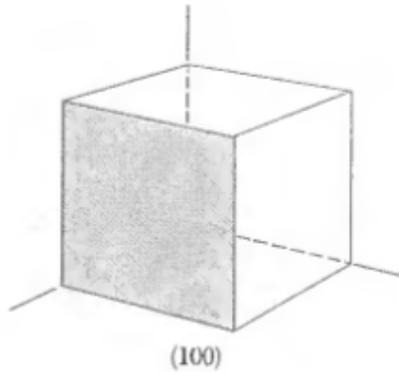
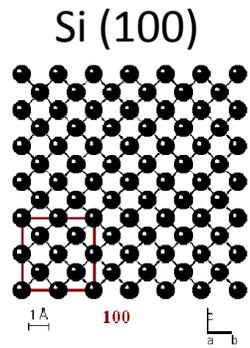
- The  $\mathbf{a}_1$  axis is the  $[100]$  direction, the  $-\mathbf{a}_2$  axis is the  $[0\bar{1}0]$  direction.
- **NB:** In *cubic* crystals, the direction  $[hkl]$  is perpendicular to the plane  $(hkl)$  having the same indices.

# Index system for crystal planes



Plane intercepts the vectors  $\mathbf{a}_1$ ,  $\mathbf{a}_2$ ,  $\mathbf{a}_3$  axes at  $3\mathbf{a}_1$ ,  $2\mathbf{a}_2$ ,  $2\mathbf{a}_3$ . Reciprocals of these numbers are  $\frac{1}{3}$ ,  $\frac{1}{2}$ ,  $\frac{1}{2}$ . Small integers having the same ratio are 2, 3, 3, thus indices of the plane are (233).

# Examples of indexed crystal planes



# Crystal Growth: Silicon and Gallium Arsenide

Advantages of Si	Advantages of GaAs
<ul style="list-style-type: none"><li>• Cheaper</li><li>• More stable and less defects, better for VLSI</li><li>• Bigger wafers</li><li>• SiO<sub>2</sub></li><li>• Pure element, easier to make</li><li>• Higher hole mobility (for CMOS)</li></ul>	<ul style="list-style-type: none"><li>• Higher electron mobility</li><li>• Higher saturation velocity</li><li>• Good for MW electronics (250GHz)</li><li>• Direct Band Gap: emits and absorbs efficiently; for LEDs, Lasers, and PVs</li><li>• Can make Al<sub>x</sub>Ga<sub>1-x</sub>As which allow HEMTs.</li></ul>

- How we make single-crystal Si and GaAs?
- How we shape into wafers?
- Characteristics of wafers?

# Manufacture of single-crystal Silicon requires high purity raw Silicon, made by the *Siemens Process*

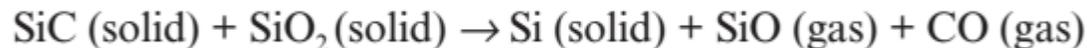


Quartzite

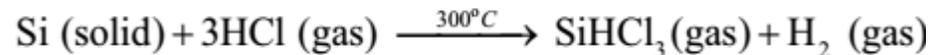
+



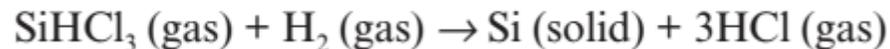
Carbon



98% pure MGS, which is then pulverized

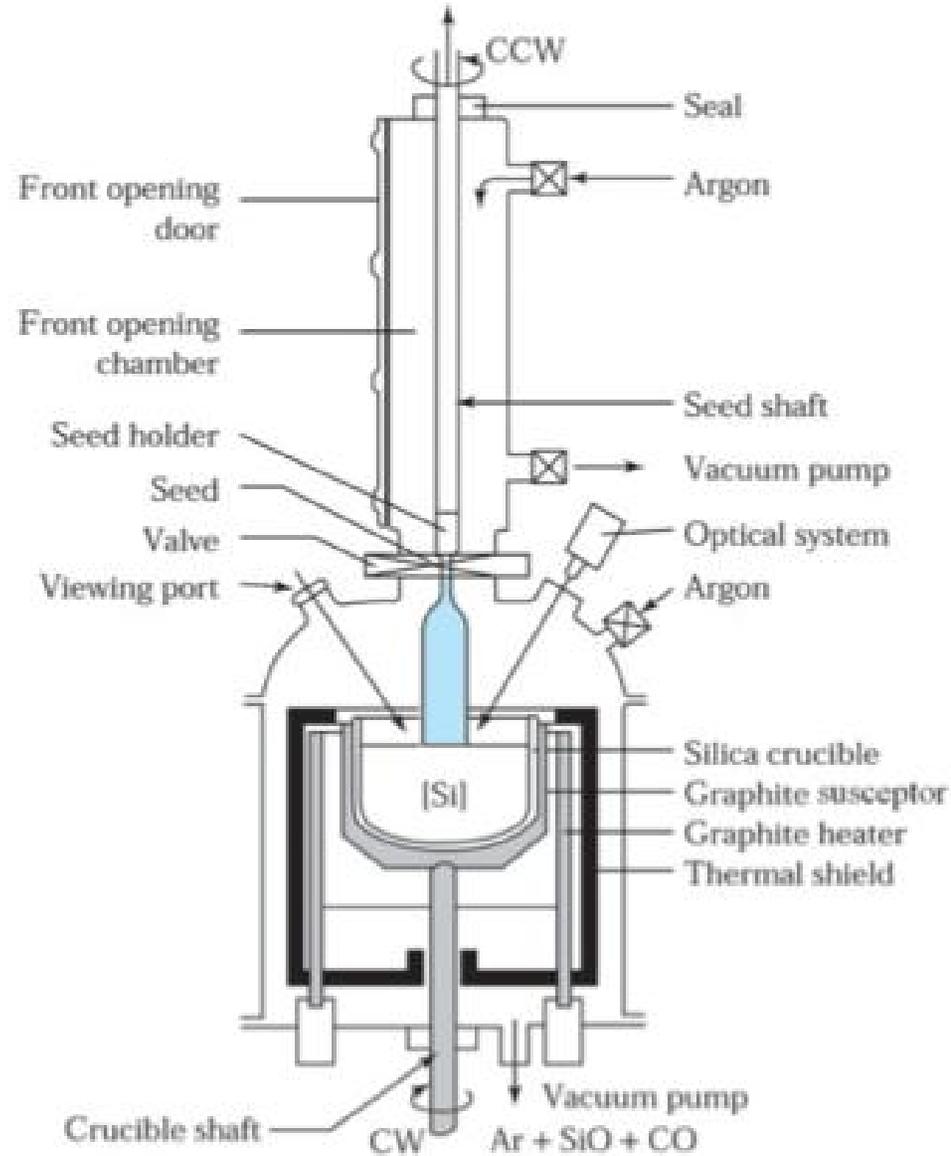


Forms trichlorosilane (boils at 32 C), which is then distilled for hydrogen reduction

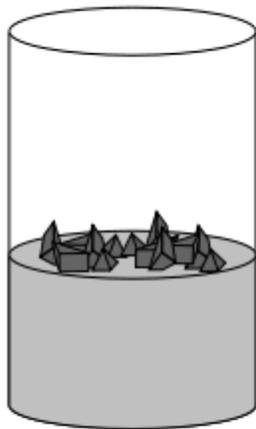
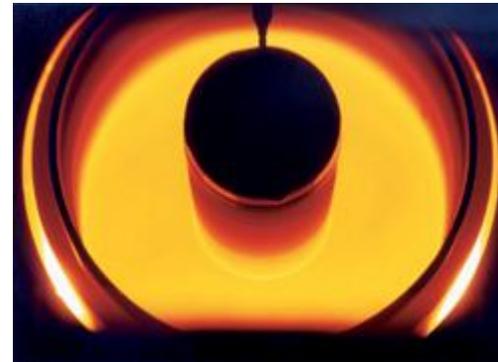


Produces very pure polycrystalline EGS on a heated Si rod in chamber.  
Impurity range is in parts-per-billion (ppb).

# The Czochralski (CZ) technique: the crystal puller

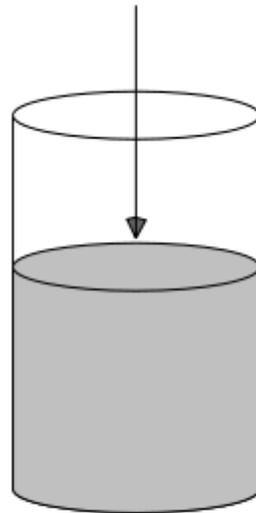


# The CZ technique in pictures



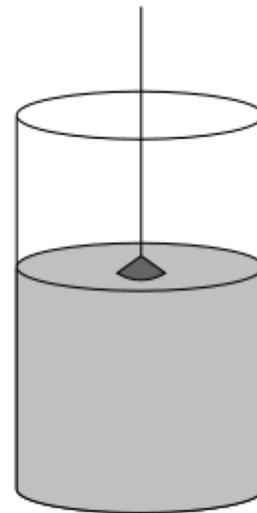
Melting of polysilicon, doping

1412° C  
Dopants  
(e.g. B)



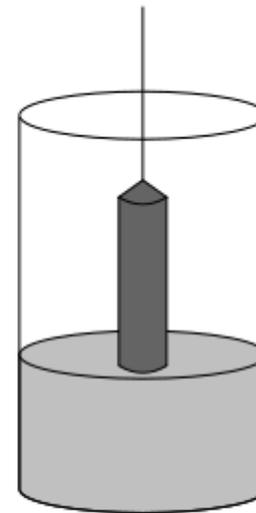
Introduction of the seed crystal

[111] or [100]

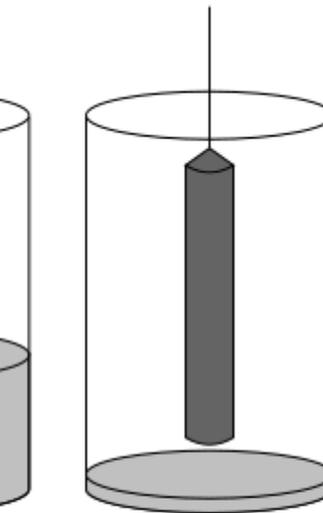


Beginning of the crystal growth

Molten Si freezes onto Si seed.



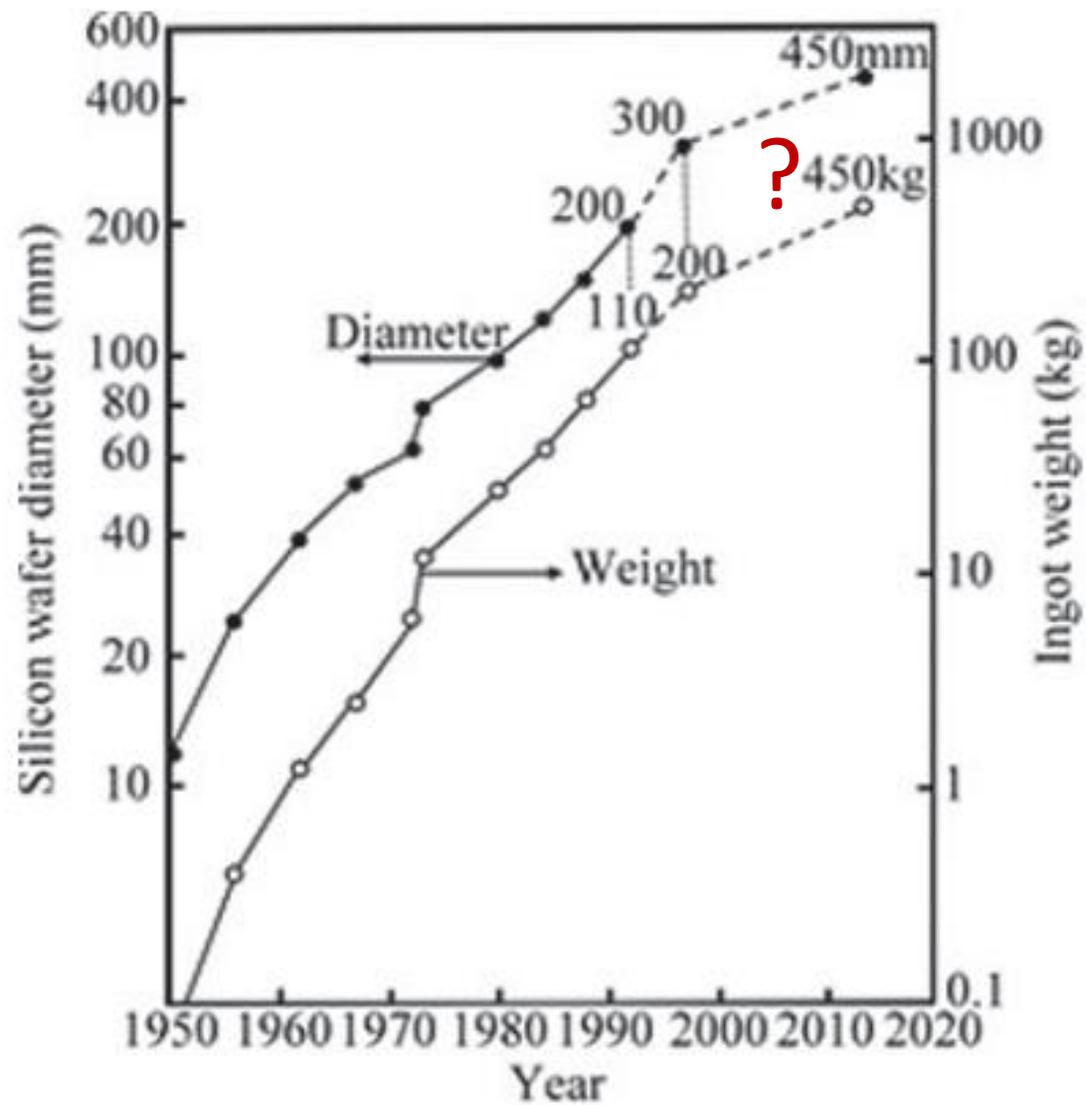
Crystal pulling



Formed crystal with a residue of melted silicon

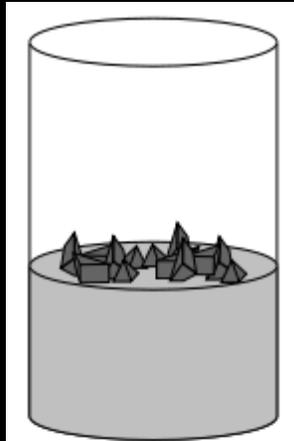
Si ingots are 200 kg in mass and 300 mm in diameter

# Wafer size projections

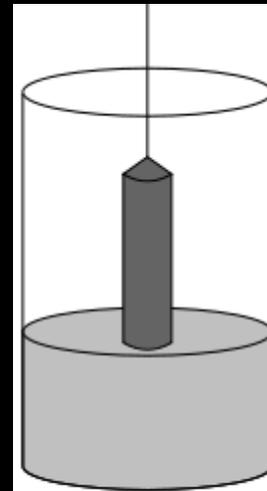


The bigger, the cheaper?

# How is do we dope Silicon?



Melting of polysilicon, doping



Crystal pulling

# Doping profiles of Silicon ingots

The concentration of dopant in liquid and solid phases of Si is not the same and changes during growth.

The *equilibrium segregation coefficient*:

$$k_0 = C_s / C_l$$



Equilibrium concentrations

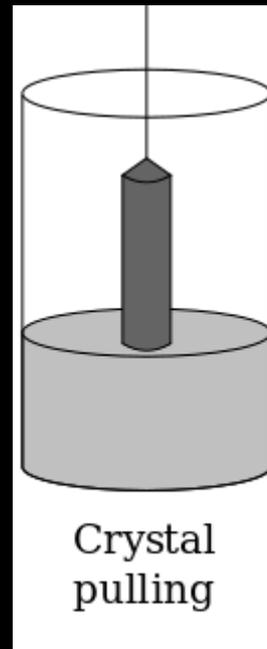
**TABLE 1 EQUILIBRIUM SEGREGATION COEFFICIENTS FOR DOPANTS IN SI**

Dopant	$k_0$	Type	Dopant	$k_0$	Type
B	$8 \times 10^{-1}$	<i>p</i>	As	$3.0 \times 10^{-1}$	<i>n</i>
Al	$2 \times 10^{-3}$	<i>p</i>	Sb	$2.3 \times 10^{-2}$	<i>n</i>
Ga	$8 \times 10^{-3}$	<i>p</i>	Te	$2.0 \times 10^{-4}$	<i>n</i>
In	$4 \times 10^{-4}$	<i>p</i>	Li	$1.0 \times 10^{-2}$	<i>n</i>
O	1.25	<i>n</i>	Cu	$4.0 \times 10^{-4}$	— <sup>a</sup>
C	$7 \times 10^{-2}$	<i>n</i>	Au	$2.5 \times 10^{-5}$	— <sup>a</sup>
P	0.35	<i>n</i>			

<sup>a</sup>Deep-lying impurity level.

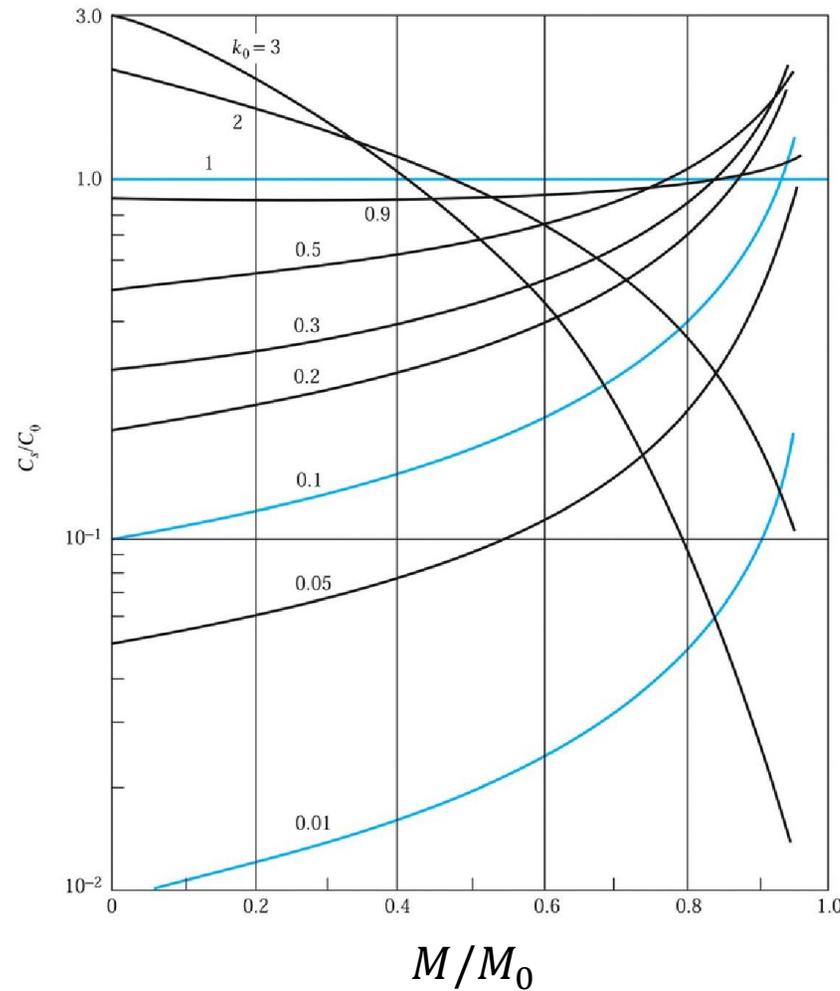
$k_0 < 1$  means dopants are rejected by solid Si into the melt, so concentration in melt increases during growth. Also, if  $C_l$  increase, then  $C_s$  will too.

How does an increasing/decreasing dopant concentration in the liquid ( $C_l$ ) affect the dopant concentration ( $C_s$ ) in a growing Si crystal?



# Doping distribution of Silicon ingots during growth

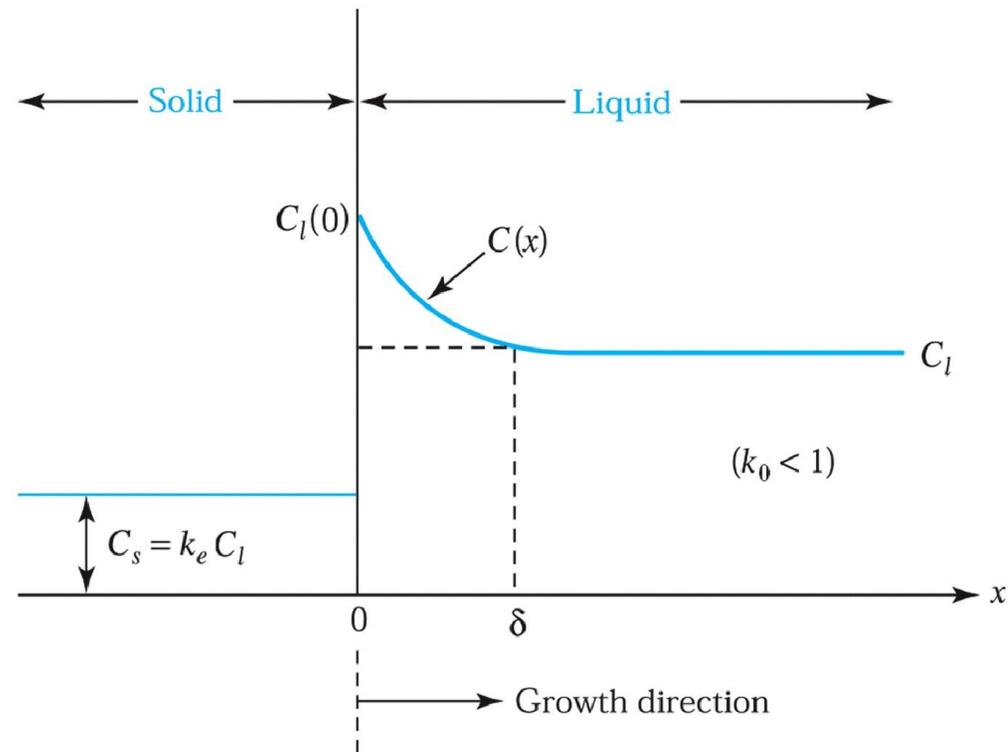
$$C_s = k_0 C_0 \left(1 - \frac{M}{M_0}\right)^{k_0 - 1}.$$



- Example

# Effective Segregation Coefficient

During crystal growth, the dopant can accumulate near the liquid-solid interface and cause a dopant concentration gradient ( $k_0 < 1$ ):



How can we model the system to account for the stagnant layer?

Mass transport by diffusion and drift